

Attorney Docket No.: F124 C1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICATION NO.: 10/664,796

APPLICANT(S): Jacob Johannes Scholtz, William Ralph Knowles, Bradley Lamar Thiel and Rene Peter Marie Schromges

FILING DATE: 09/18/2003

TITLE: Particle-Optical Device and Detection Means

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, Va 22313-1450

Pursuant to the guidelines for Information Disclosure Statements, 37 C.F.R. §§ 1.97-1.98, attached hereto is PTO Form 1449 (one sheet) with references listed for consideration by the Office.

In accordance with 37 C.F.R. § 1.98(a), copies of the listed written references are being provided. Copies of the U.S. patents are not provided in accordance to recent USPTO office policy.

In accordance with 37 C.F.R. §§ 1.97(g)-(h), the filing of this Information Disclosure Statement shall not be construed as a representation that a search has been made or an admission that the information cited in the statement is, or is considered to be, material to patentability as defined in 37 C.F.R. § 1.56(b).

This Information Disclosure Statement is being filed before the mailing of a first Office action on the merits.

Respectfully submitted,

Date: 3/5/04

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CERTIFICATE OF MAIL

I hereby certify that this paper or fee is being deposited with the United States Postal Service via First Class Mail to Addressee, under 37 CFR 1.10, on the 5th day of March, 2004, and is addressed to the Mail Stop Missing Parts, ommissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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PTO/SB/08A (08-03)

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Substitute for form 1449/PTO

Sheet

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Complete if Known			
Application Number	10/664,796		
Filing Date	09/18/2003		
First Named Inventor	Jacob Johannes Scholtz		
Art Unit			
Examiner Name			
Attorney Docket Number	F124C1		

U. S. PATENT DOCUMENTS							
Examiner Initials*	Cite No.1	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant		
		Number-Kind Code ^{2 (if known)}			Figures Appear		
	Α	^{US-} 6,365,896	04-02-2002	Van der Mast			
	В	^{US-} 6,184,525	02-06-2001	Van der Mast			
	С	^{US-} 6,172,363	01-09-2001	Shinada et al.			
	D	^{US-} 5,578,821	11-26-1996	Meisberger et al.			
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FOREIGN PATENT DOCUMENTS							
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	Е	JP05-174768 Pat. Abstract of Japan	07-13-1993	Nikon Corp.	•		
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Signature	Considered	

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Substitute for form 1449/PTO		Complete if Known			
- Substitute for form 1440/110				Application Number	10/664,796
INFO	ORMATION	I DIS	CLOSURE	Filing Date	09/18/2003
STATEMENT BY APPLICANT		First Named Inventor	Jacob Johannes Scholtz		
				Art Unit	
(Use as many sheets as necessary)		Examiner Name			
Sheet	2	of	2	Attorney Docket Number	F124C1

		NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	F	C.K. CRAWFORD, Charge Neutralization Using Very Low Energy Ions, Scanning Electron Microscopy, 1979, II, SEM INc., USA	
	G	ALBERT FOLCH ET AL., High Vacuum Versus, "Environmental" Electron Beam Deposition, Jul/Aug. 1996, B 14(4), PP. 2609-2614, J. Vac. Sci.	
	Н	YUKINORI OCHIAI, Electron-Beam-Induced Deposition of Copper with Low Resistivity, Nov/Dec. 1996, B 14(6), PP. 3887-3891, J. Vac. Sci. Technol	
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Examiner	 Date	
Signature	Considered	

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